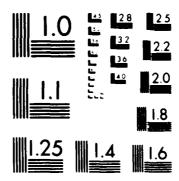
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19 ABSTRACT (Continue on reverse if necessary and identify by block number)							
Ion plating is a physical vapor deposition process which uses a plasma to modify the							
microstructure/microchemistry of thin film coatings. This research has directly shown							
that processing variables such as plasma energy/density; substrate temperature; deposition							
rate; and substrate surface chemistry directly effect the deposited film microstructure							
and chemistry. This processing technique allows mechanically strong/chemically graded							
interface layers to be produced between dissimilar materials. Film adhesion with this							
process is correspondingly excellent. This process was used to produce corrosion and wear							
resistant hard coatings. —							
In a related portion of this program, a model was developed to explain experimental							
observations for thin film nucleation mechanisms. The analytical excressions developed							
were able to closely model film nucleation and showed that preferential nucleation at							
defect sites and the dissociation of small clusters are controlling factors for thin film nucleation based on an island growth model.							
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ION PLATING: FUNDAMENTAL PROCESSING STUDIES AND SYNTHESIS OF HIGH PREFORMANCE COATINGS

FINAL REPORT

J. M. Rigsbee

August 4, 1987

U. S. Army Research Office

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Dept. of Materials Science & Engineering University of Illinois at Urbana-Champaign 1304 West Green Street Urbana, Illinois 61801 (INSTITY)

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FINAL REPORT

Statement of Problem

Ion plating is a physical vapor deposition process involving the ceposition of a coating under continuous bombardment with low to medium energy ions. Coatings deposited by this process are recognized to have excellent physical properties and to be very useful under corrosion and wear conditions. In spite of the attractiveness of these coatings, little basic research has been done to understand how the many processing variables (e.g., ion energy and flux, substrate cleanliness and temperature, and deposition rate) affect the structure, chemistry and physical properties of these coatings. This was the major emphasis of this research program. This program also was concerned with obtaining a better understanding of thin film nucleation mechanisms. Primarily, the approach was to develop analytical expressions to model the effects of surface defects and small cluster dissociation on film nucleation via an island growth model. These expressions were compared with experimental data.

Summary of Results

This effort has yielded a much improved understanding of ion plated films and how processing variables influence the structure and chemistry of such films. Basically, the continuous ion bombardment during film growth promoted improved film density and adhesion. The film density is improved through conversion from a usual collumnar growth mode (for no ion bombardment and low growth temperatures) to an equiaxed growth mode. Film adhesion is improved through the development of a chemically graded interface between the coating and substrate (this allows reduction of residual stress and thermal expansion coefficient difference effects). These studies mainly studied metal/metal elemental systems.

Other experimental efforts centered about production of titanium nitride and mixed oxide coatings through reactive ion plating. This work was done cooperatively with the U.S. Army Corps of Engineers Construction Engineering Research Laboratory. These coatings have uses ranging from corrosion to EMI/EMP. This interactive work is continuing.

The thin film nucleation modeling work was extremely productive. Analytical expressions were developed whigh significantly improved the ability to predict experimental results. This work showed that the dissociation of small clusters is a large contibution to the nucleation process, in direct conflict with other theoretical studies but in good agreement with available experimental data. Also, substrate surface defect density was shown to be critical and ofter rate controlling. Experimental efforts in this area are continuing.

Participating Scientific Personnel

- J. M. Rigsbee, Principal Investigator
- Y. W. Lee, completed Ph.D. degree in February, 1986 continued as Post Doc on this project and in association with USA-CERL
- J. C. Logas, completed M.S. degree in May, 1987
- H. S. Savage, completed M.S. requirements, degree to be awarded in Fall 1987
- D. M. Leet, completed M. S. degree in December, 1984

Degrees: Master of Science -- 3

Doctor of Philosophy -- |

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